

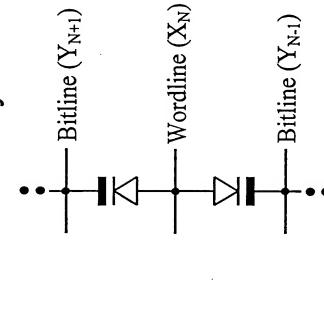
#### Agenda

- Memory cell
- Fabrication process
  - Device organization
- Write operation
- Read operation
- Bit area comparison
- Summary

#### Memory Cell (1/3)

Two-terminal cell contains a diode and antifuse.

 Wordlines and bitlines are shared between layers.



cathode

Antifuse 📉

Bitline (Y)

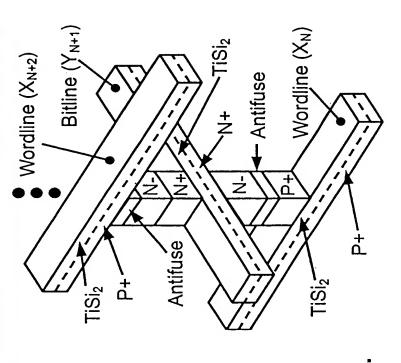
anode

Wordline (X)

Fig. 2

### Memory Cell (2/3)

 Cells built from polycrystalline silicon.

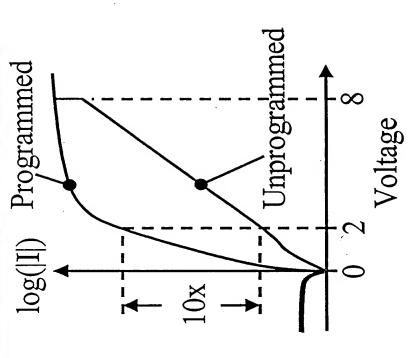


Stacked for maximum density.

### Memory Cell (3/3)

- Cell states:
- Unprogrammed "1": initial state of all cells.
- Programmed "0":Antifuse oxide is ruptured, leaving the diode.





### **Process Highlights**

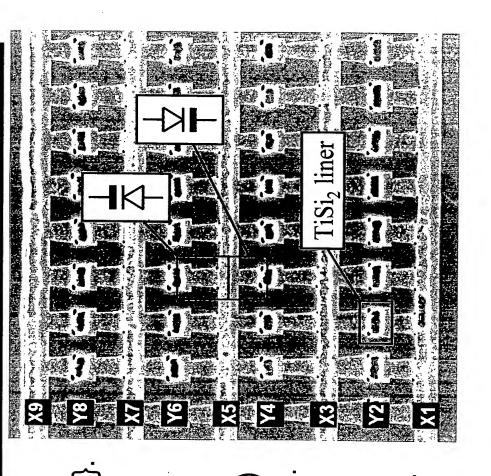
- 0.25µm Nwell CMOS:
- Single 17.5nm gate oxide;
- 2 tungsten layers ("R1" and "R2") for transistor interconnect.
- 8-high stack of memory cells:
- 5 wordline layers, 4 bitline layers;
- Cell is  $0.50 \mu m \times 0.50 \mu m \times (1/8)$ ;
- Vias from array to CMOS.
- 1 Al layer for bond pads, global signals and power distribution.

# Array of Stacked Memory Cells

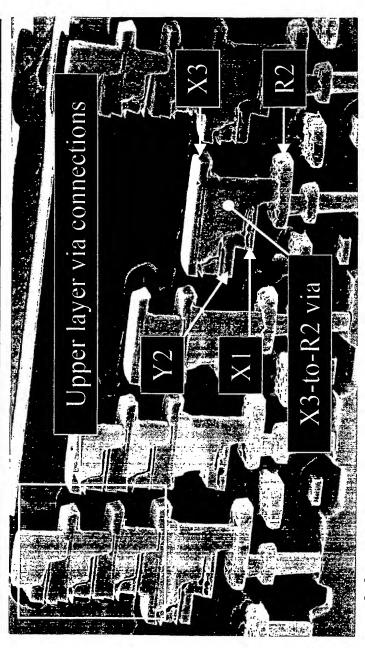
Wordlines:

X{1, 3, 5, 7, 9}.
Bitlines:
Y{2, 4, 6, 8}.
(8+1) wiring
levels give (8)
layers of cells.

TiSi<sub>2</sub> liners reduce sheet rho (2-3 Ω/□)



# Connections to the Array



/ertical interconnects span 3 memory layers; 4 via masks service 9 layers.

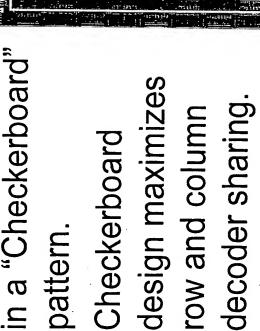
#### Tile Organization

- · Cells built in 1MB sub-arrays ("Tiles"):
- 1024 wordlines x 1024 bitlines x 8 layers;
- Additional wordlines and bitlines for test and repair.
- circuits, and sense amplifiers laid out Row and column decoders, bias beneath the 1MB Tiles.
- 2+s transistors per memory line, where ε is the amortized cost of the decoders and bias circuits.

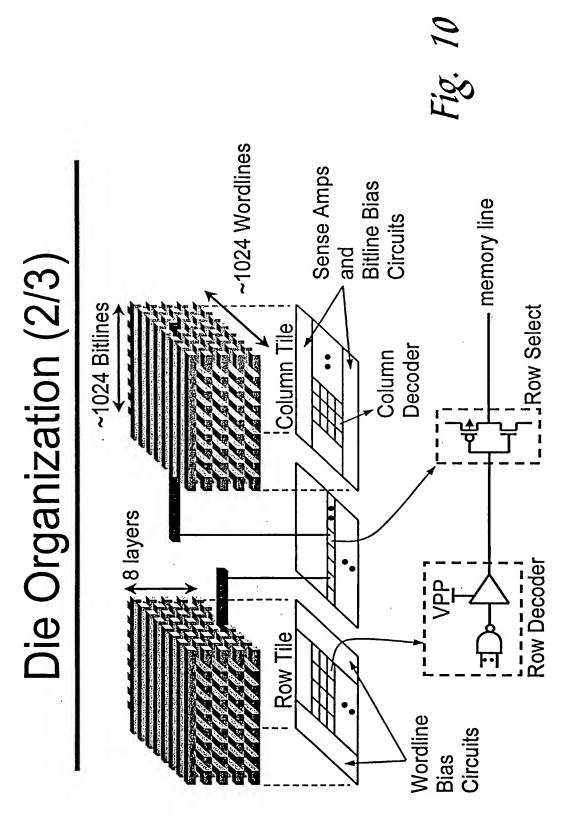
## Die Organization (1/3)

1MB Tiles organized in a "Checkerboard" pattern.

decoder sharing. row and column Checkerboard

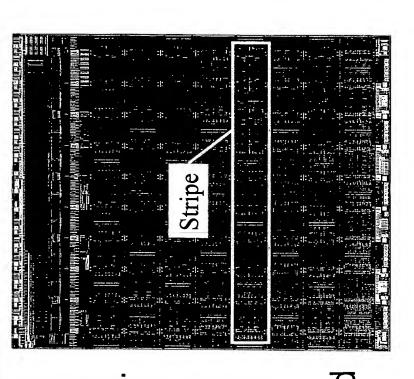






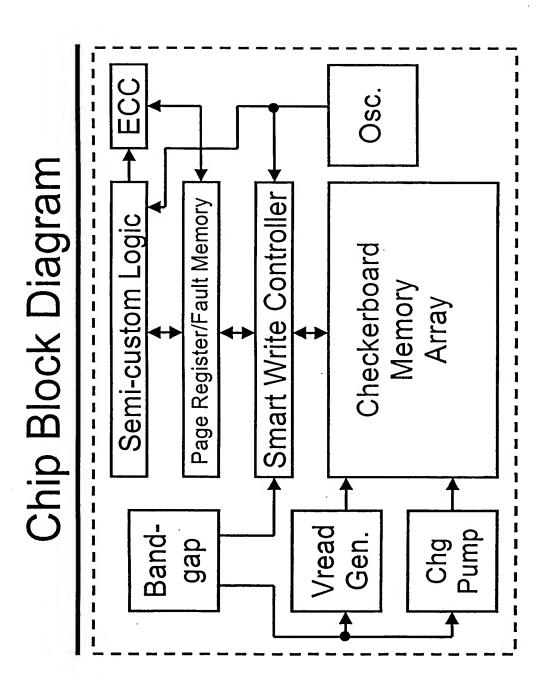
## Die Organization (3/3)

- Chip contains 8
   horizontal Stripes,
   with 9 Tiles/Stripe
- User pages are distributed among
   8 Tiles in a Stripe.
- 9th Tile in each Stripe is dedicated to ECC.



#### Fault Tolerance

- Single-bit correction, double-bit detection ECC included on the die:
- (72,64) Hamming code protection on each 64-bit "octbyte";
- 8 additional syndrome bits per 64 user bits;
- ECC is performed 100% on-chip; external system is unaware of ECC operations.
- Flexible row repair allows factory or onthe-fly (field) replacement.



Write Operation (1/2)

### Write Operation (2/2)

- Smart Write block:
- Skips over "1" bits;
- Uses the read sense amp to dynamically detect when an antifuse ruptures;
- Immediately proceeds to the next bit, accelerating writes.
- Detects programming fails.
- data + 1B ECC) initiates reprogramming More than one fail in an ECC word (8B to a redundant page location.

#### Read Operation

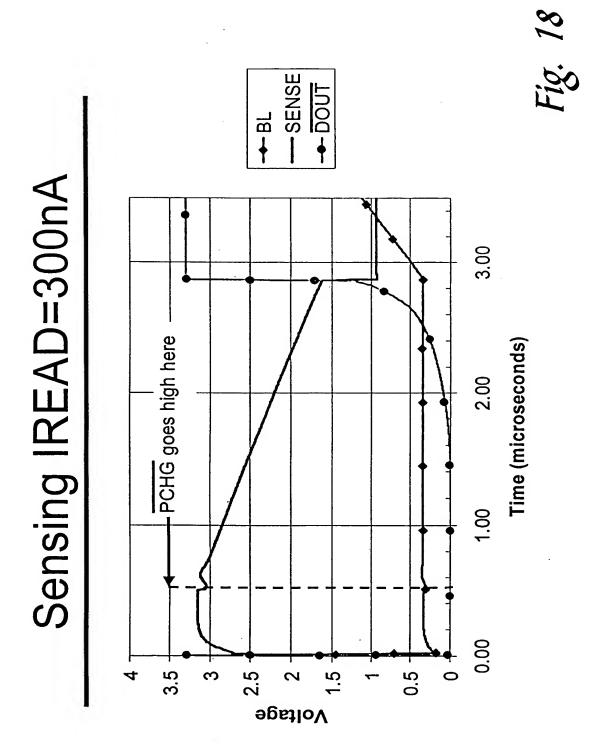
- Wordline = 2.4V = "Vread".
- Bitline = Dummy bitline = 0.4V:
- Dummy bitline provides common mode cancellation of array noise.
- Current-mode sensing:
- Active mirror clamps memory cell voltage to 2.0V, cell current is compared to IREF.
- 72 sense amps active simultaneously:
- All 9 Tiles in a Stripe are active;
- Memory cells above Row Tiles are read with sense amps located in adjacent Stripes.

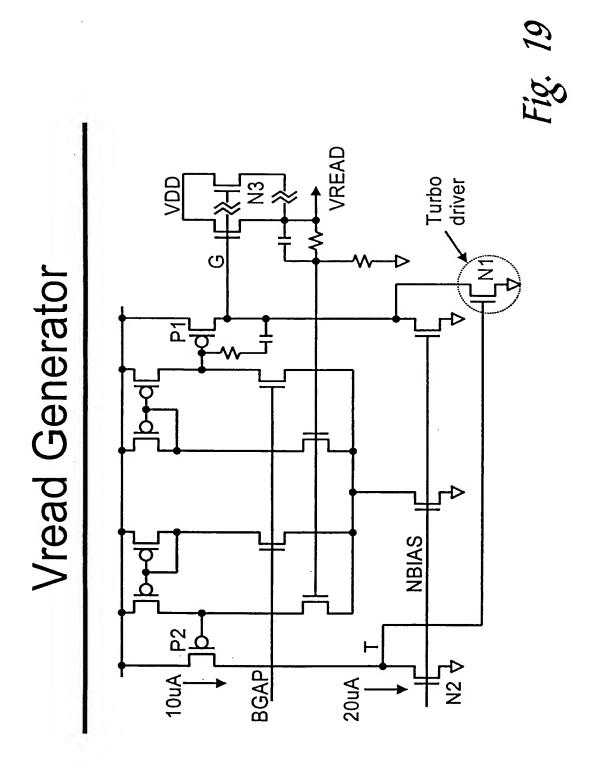
BL (0.4V)

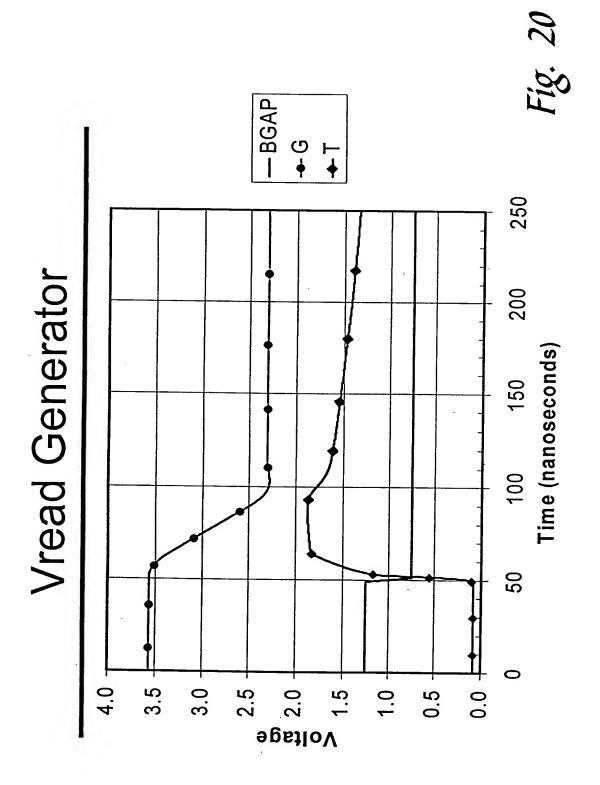
Read Sense Amplifier

Z

Z









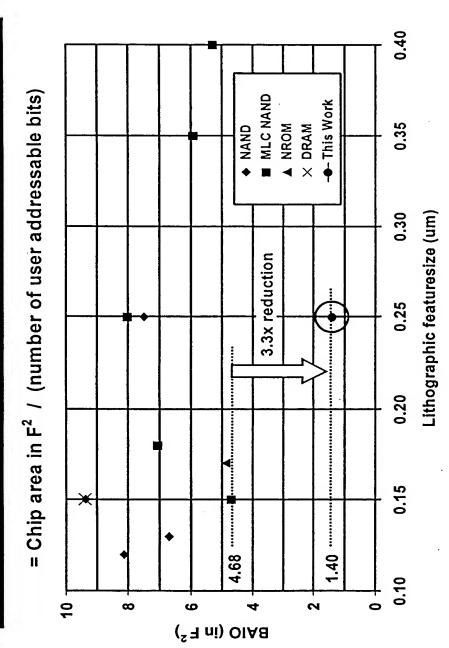


Fig. 21

Technology	0.25um CMOS, Tox = 17.5nm
Cell type	OTP, diode+antifuse, 0 transistors
Cell size	0.50um X 0.50um
Chip size	6.7mm X 7.2mm = 48.3mm <sup>2</sup>
Wiring	2 layers W + 1 layer Al
Power	VDD = 2.7 - 3.6V IDD = 30mA
Bandwidth	1.0 MB/s read, 0.5 MB/s write
Organization	128K pages X (512 + 16) bytes/page
Fault tolerance	(72,64) modified Hamming ECC
Application	Digital media, handhelds, file storage

#### Summary

- 3-dimensional memory array with cells vertically stacked 8-high.
- Two terminal, antifuse/diode memory cell built in polysilicon.
- 512 Mbit PROM, generic NAND Flash interface.
- SEC-DED ECC included on-die.
- 3.3x more bits per F2 than MLC NAND Flash.